



Att. Docket No. 10191/1629

AF  
1765  
JG

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Appl. Serial No. : 09/720,761

Confirmation No. 5642

Title : METHOD OF PLASMA  
ETCHING OF SILICON

Applicant(s) : Franz LAERMER et al.

Filed : March 26, 2001

TC/A.U. : 1765

Examiner : Kin Chan Chen

Docket No. : 10191/1629

Customer No. : 26646

MAIL STOP AF

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

I hereby certify that this correspondence is being deposited with the  
United States Postal Service with sufficient postage as first class mail  
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on

Date: 10/14/2004

Signature: [Signature]

AARON C. DEDITCH  
(33,865)

**TRANSMITTAL**

SIR:

Transmitted herewith for filing in the above-identified patent application is an Amendment  
After A Final Office Action.

This is also a Petition under 37 C.F.R. § 1.136(a) to extend the three-months response date  
by two months from September 7, 2004 to November 7, 2004.

The Commissioner is authorized to charge the appropriate fees, which are believed to be  
**\$430.00** for the two-months extension, to Deposit Account No. **11-0600**, and is also authorized, as  
appropriate and/or necessary, to charge any additional fees (including any Rule 136(a) extension  
fees) or credit any overpayment to Deposit Account No. **11-0600**. Two duplicate copies of this  
transmittal letter are enclosed for that purpose

Respectfully submitted,

Dated: 10/14/2004

By: [Signature]

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**CUSTOMER NO. 26646**

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